Vacuum Drying Oven(ZK/VC Series)

Vacuum Drying Oven is specially designed for drying heat-sensitive, decomposable, and oxidizable substances. Capable of inerrt gas infusion, enabling rapid drying of complex materials.

- Reference standard: GB/T 29251-2012 vacuum drying chamber;
- ◆ Structural Design:More rational structural design for enhanced operational simplicity: Optimized sample rack layout for improved accessibility and efficiency
- ◆ Internal material: The studio is made of mirror faced stainless steel plate material, ensuring that the product is durable and easy to clean;
- ◆ Control system: Microcomputer digital temperature controller with timing function, precise and reliable temperature control;
- Control precision: Constant temperature fluctuation: ± 1 °C;
- Temperature precision: 0.1 °C; The vacuum degree can reach 133Pa;
- ◆ Door structure: Tempered and bulletproof double layer glass doors allow for clear observation of objects in the studio at a glance;
- ◆ Seal ring: The door closure is adjustable, and the synthetic silicon door seal ring is formed as a whole to ensure keep high vacuum inside the chamber;
- Power: AC220V ± 10% 50Hz (380V for 6500ZK);

StabilityChamber

◆ Optional: program table, inert gas intake valve, drying tank, oil filter, etc.

VC series vacuum drying oven is equipped with a vacuum pump as standard, and is equipped with a resistance silicon tube pressure sensor to achieve digital display of vacuum degree. It can also achieve continuous vacuum drying by setting the upper and lower limits of vacuum degree and the number of cycles, improving experimental or production efficiency.

◆ Control system: Touch screen controller with timing function, precise and reliable temperature control;

- Control precision: Constant temperature fluctuation: ± 1 °C; Temperature precision: 0.1 °C;
- Vacuum precision: Equipped with resistance silicon tube pressure sensor, vacuum data display, control precision of ± 1%;
- Standard configuration: Vacuum pump.

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	Internal structure	♦ 6090VC~6210VC	◆ 6090ZK

